

Notice of References Cited

Application/Control No.

09/657,055

Applicant(s)/Patent Under
Reexamination
FUKIAGE, NORIAKI

Examiner

Hung K. Vu

Art Unit

2811

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-			
	B	US-			
	C	US-			
	D	US-			
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	F	US-			
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FOREIGN PATENT DOCUMENTS

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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Gesheva et al., "Deposition of Characterization of CVD-Tungsten and Tungsten Carbonitrides on (100) Si", Ceramics International 22, 1996, pp. 87-89.
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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